Title: Advanced Instrumentation – Electron Microscopy

Marking scheme:

marks issues addressed in answer 5 BF image: upper layer shows diffraction contrast, hence the upper layer must be crystalline 5 BF image: upper layer appears dark, i.e. has higher mass absorption contrast, thus it is probable more dense and/or has heavier atoms in it 10 SAED from both layers reveals very similar structures typical of <110> zone axes in cubic structures $(1:\sqrt{2})$ aspect ratio, 2 mirror planes). Note that the projection is not hexagonal because there is no six-fold symmetry (though it may appear so at first glance) 10 SAED from interface region shows one common set of reflections, indicating orientational relationship 10 HREM image shows perfect epitaxy between two crystalline materials with very similar lattice fringe contrast. The upper layer appears somewhat darker, again indicating stronger scattering. 10 The fringe spacings observed in HREM are ~0.28nm and ~0.33nm, corresponding roughly to Si (200) and (111) planes, but could really represent almost any **semiconductor** (e.g. (Al)GaAs, Ge). 10 EDX spectrum shows presence of 6 lines. These 6 candidates are: C (K-line, contamination), O (K-line, surface oxidation), quite strong but not directly identifiable line just below 1keV (Ni Lline, but could be any transition metal L-line (Co, Ni, Co); Ne K would make no sense for chemical compound), Si (K-line, strongest), Ni K line (second strongest; must be from sample), Cu (K-line, presumably from grid) 20 EELS reveals only Ni M and Si K edges, hence no Co or Cu; Ni and Si signals are both roughly

- equally strong, but as Si L has lower cross-section than Ni M there must be **more Si than Ni** in the sample
 only Si and Ni with a bit of C and/or O are left as candidates, possible compounds: nickel silicides
- only Si and Ni with a bit of C and/or O are left as candidates, possible compounds: nickel silicides (silicon carbides and oxides would be lighter, contradicting the observed strong mass absorption contrast)
- the **only nickel silicide that is Si-rich and has a cubic structure similar to the diamond lattice** of Si is NiSi₂ (CaF₂-type structure). So the structure should be NiSi₂ on Si, a system of great importance to the computer industry for fabrication of metal contacts onto silicon, e.g. for MOSFETs. Both are cubic face-centred structures with very similar lattice parameters of a_{Si} =0.5431nm and a_{NiSi2} =0.5406nm (the latter is only 0.5% smaller).

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